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Disclosure No. 03-0512.00/US**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**Form PTO-1449 (Modified)
(Use several sheets if necessary)**COMPLETE IF KNOWN**

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First Named Inventor	Larry D. Kinsman
Group Art Unit	2873
Examiner Name	Loha Ben
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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
lw		6,407,381	B1	Glenn et al.	06/18/2002	
lw		2004/0038442	A1	Kinsman	02/26/2004	
lw		2004/0041261	A1	Kinsman	03/04/2004	
lw		10/893,022		Hall et al.	07/16/2004	
lw		10/901,851		Derderian et al.	07/28/2004	
lw		10/915,180		Street et al.	08/10/2004	
lw		10/927,550		Derderian et al.	08/26/2004	

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T
lw		DuPont Electronic Materials, Data Sheet, Pyralux PC 2000 Flexible Composites, 4 pages, October 1998, < http://www.dupont.com/fcm >.	
lw		Micro Chem, Nano SU-8, Negative Tone Photoresist Formulations 50-100, 4 pages, February 2002, < http://www.microchem.com/products/pdf/SU8_50-100.pdf >.	
lw		BRUBAKER, C. et al., "Ultra-thick Lithography for Advanced Packaging and MEMS," SPIE's 27 th Annual International Symposium on Microlithography 2002, March 3 - 8, 2002, Santa Clara, CA.	
lw		AUSTIN, M.D. and S.Y. CHOU, "Fabrication of 70 nm channel length polymer organic thin- film transistors using nanoimprint lithography," Applied Physics Letters, Vol. 81, No. 23, pp. 4431-4433, December 2, 2002, American Institute of Physics.	

EXAMINER LOHA BEN	DATE CONSIDERED 4/20/05
*EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application(s).	